

JC12 Rec'd PCT/PTC 11 APR 2005

April 11, 2005

Patent Application  
Preliminary Amendment  
Docket No. PI-128

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Hyun Soo Roh; Tae Won Park; Kill Sung Lee; In Kyung Lee

Docket No. : PI-128

For : Slurry Composition for Secondary Polishing of Silicon Wafer

Mail Stop PCT

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

This application is a National Stage Application of International Application Number PCT/KR2003/01532. Please amend the above-identified patent application as follows:

**Amendments to the Specification** begin on page 2 of this paper.

**Remarks** follow the amendment sections of this paper.